Stress Measurements using the Picosecond Ultrasonic Method

Chris Korabik

PI: Professor Oluwaseyi Balogun

Mentors: Matt Ford, Li Zhang, Baojie

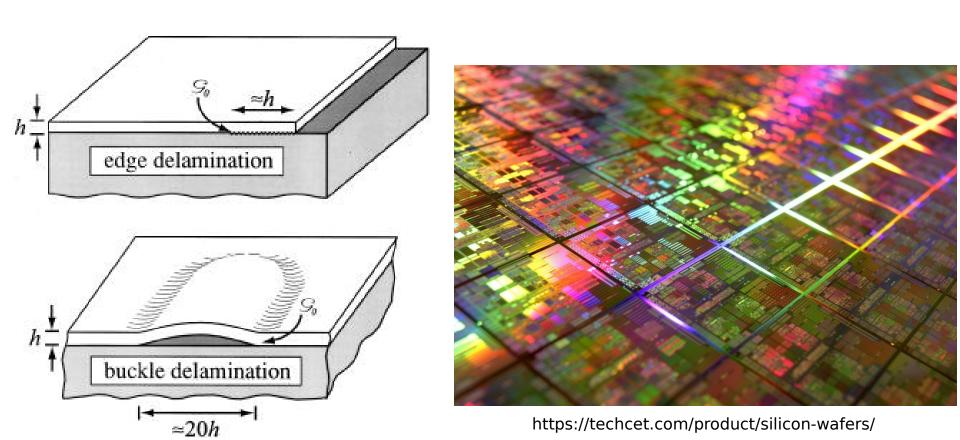
Lu, Hong-Cin Liou

Acknowledgements

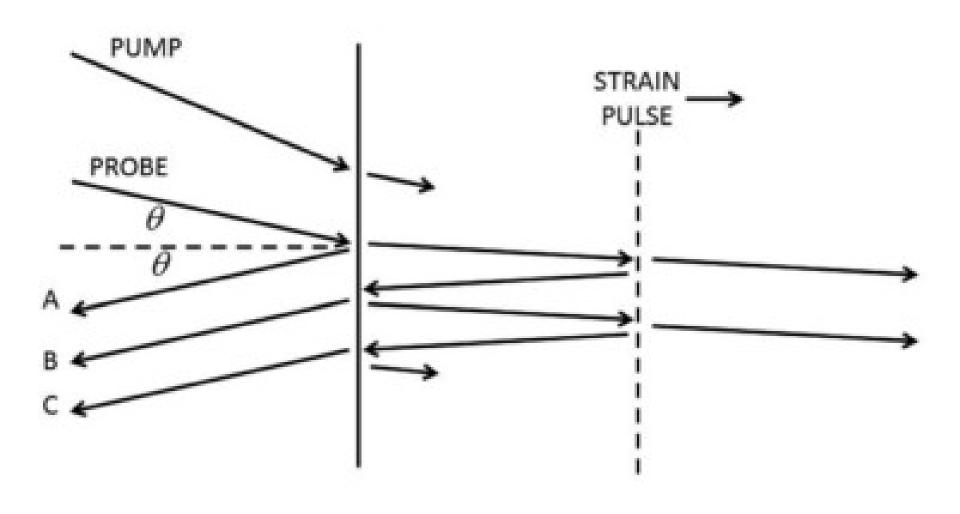
- Professor O. Balogun and his research group
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Stresses in thin films

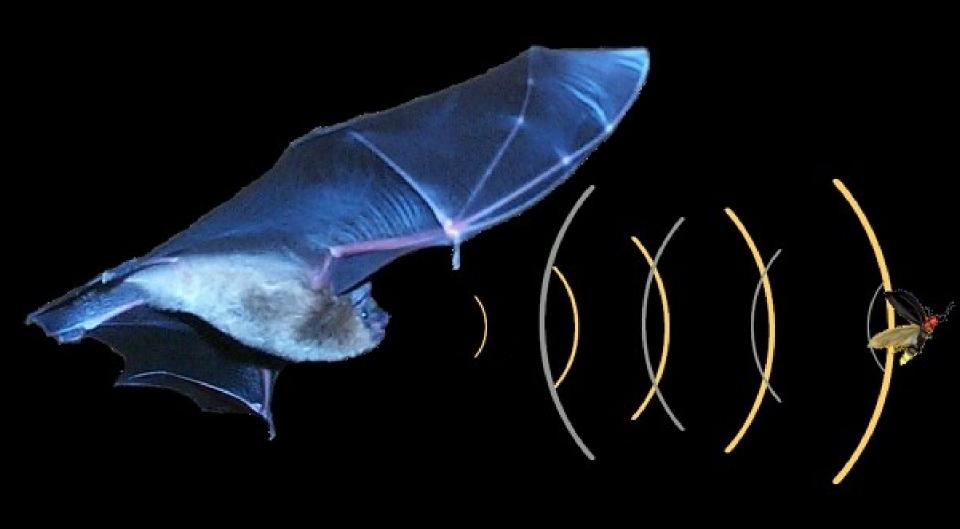


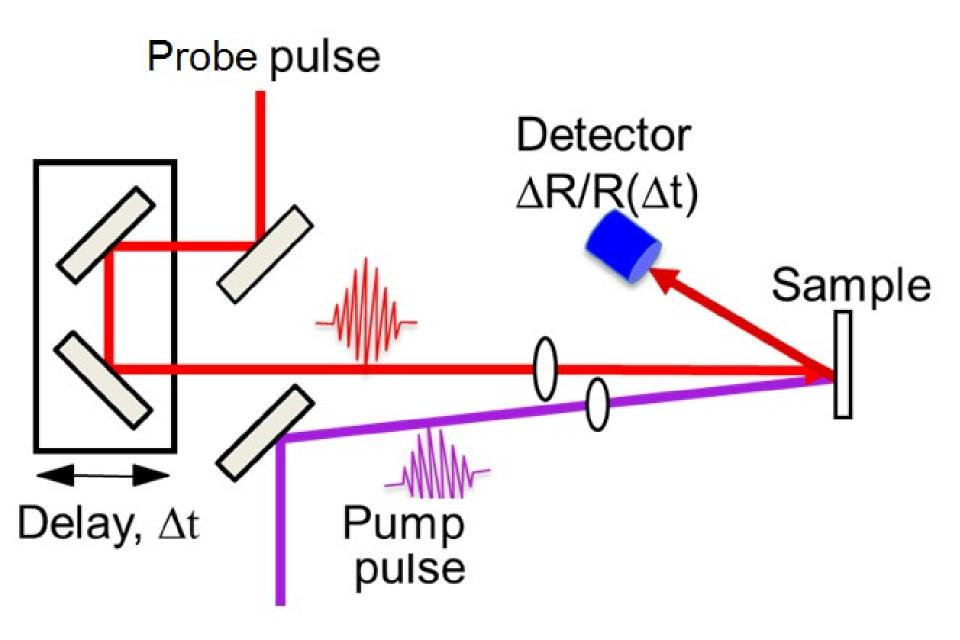
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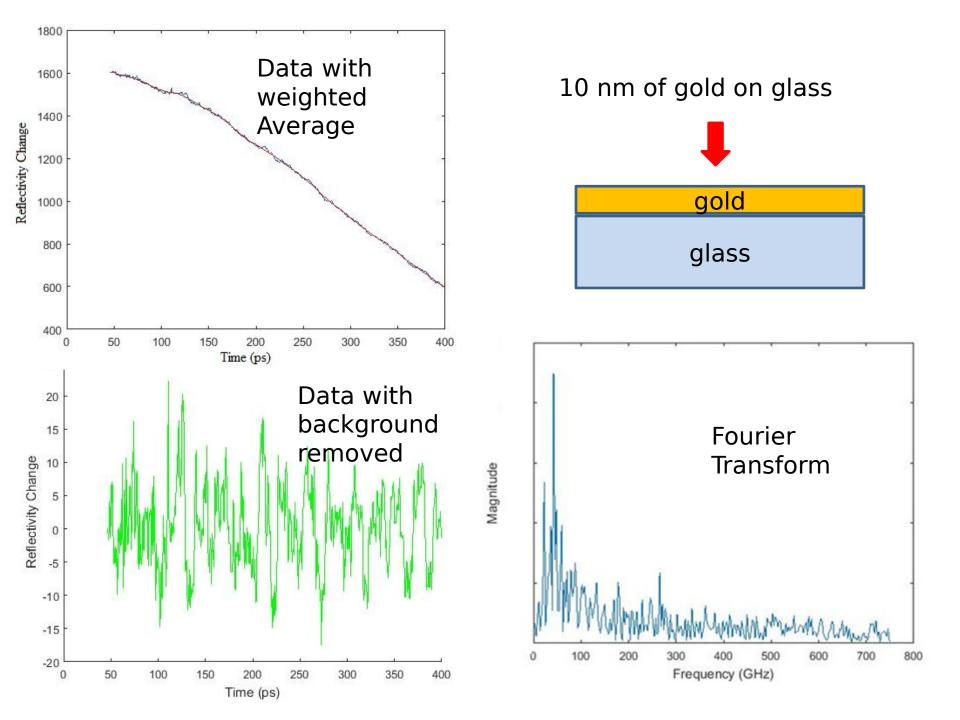
SUBSTRATE

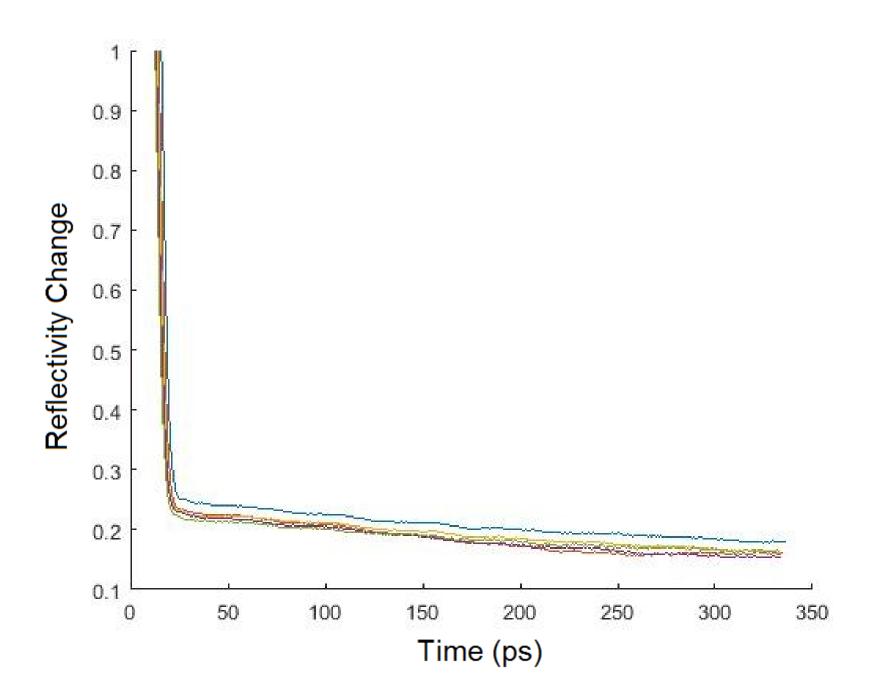
Dai et al. Journal of Applied Physics 119. 2016.

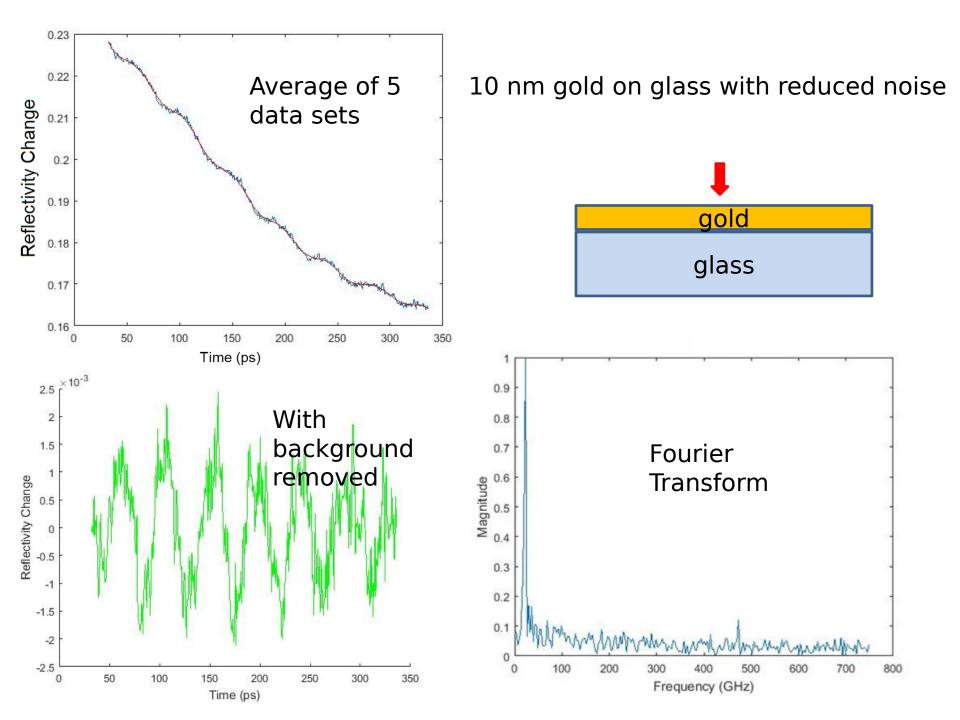


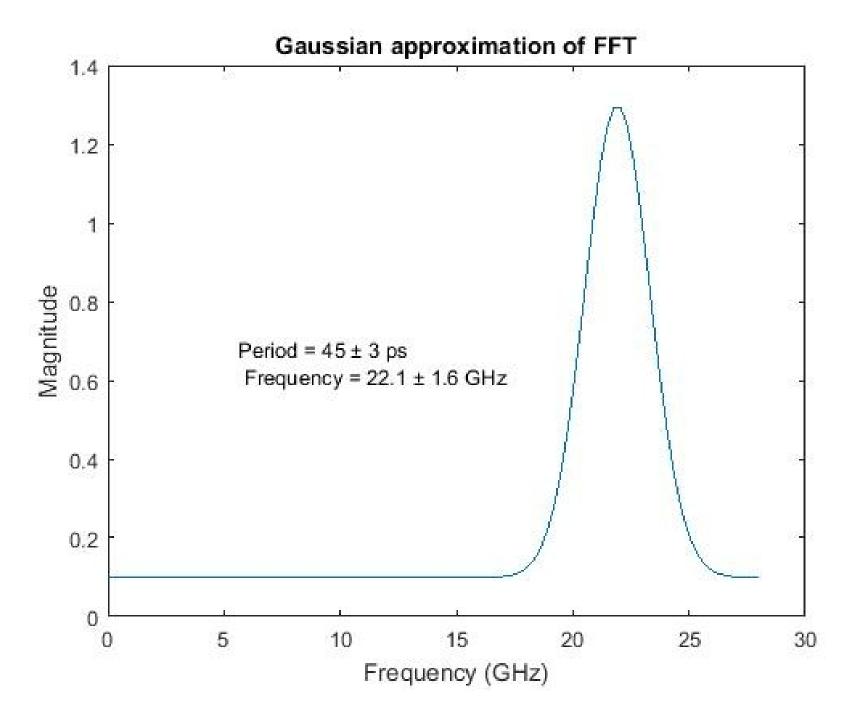






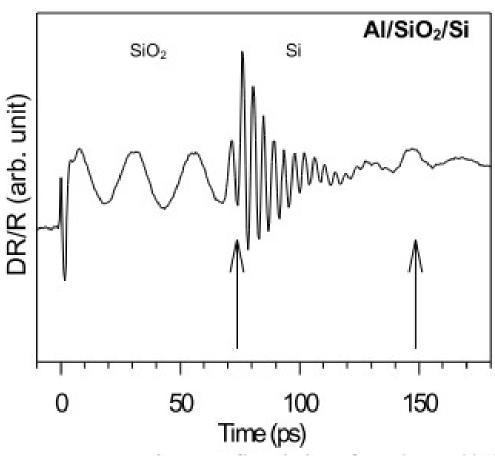




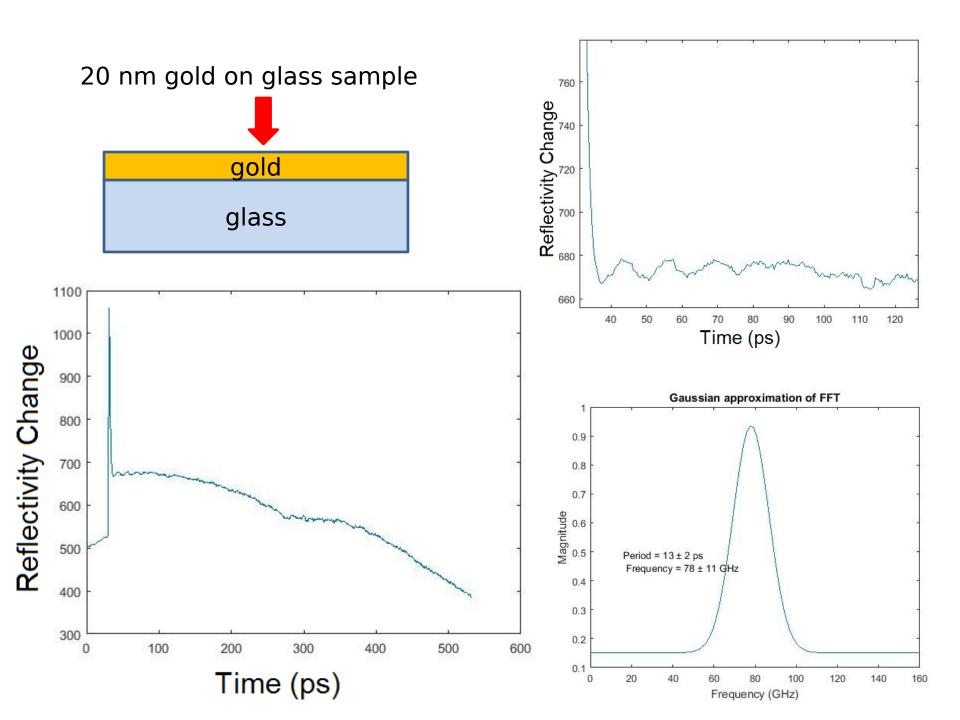


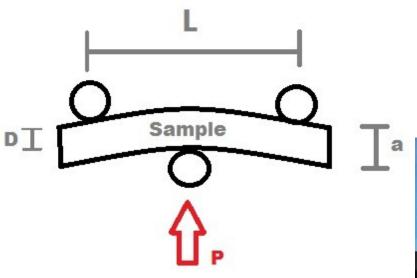
Al SiO₂

$$\tau = \frac{\lambda_0}{2 n v \cos \theta'}$$

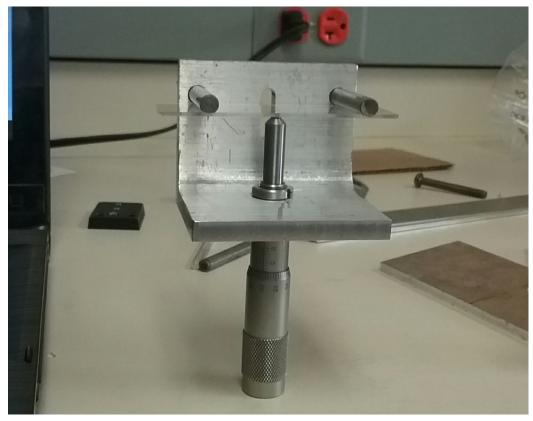


Devos et al. WCU. 2003.





$$\epsilon = \frac{6Da}{L^2} \qquad \quad \sigma = E\epsilon$$



Conclusions

- High signal-to- noise ratio is essential
- 3 point bend setup created
- Specific stress measurements can be made
- This can help optimize performance of electronic devices

References

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